REMARKS/ARGUMENTS

Claims 5-16 are pending. Claims 5-9 and 12-14 have been rejected over JP '413 to Mitsuyoshi et al. in view of Park et al. '230. Claims 10-11 and 15-16 have been rejected over the foregoing references, and further in view of Miyazaki et al.

In response, claim 5 has been amended to recite, in part –

a controller for controlling a processing time for immersing said substrates to be treated, said controller comprising: . . .
a storage device for storing beforehand a relationship between said count of the substrates and a processing time such that <u>a processing time for immersing said substrates in the heated treating solution is progressively extended as said count of said substrates increases, and such that a fixed processing time is assigned to a predetermined range of counts of said substrates</u> . . . .
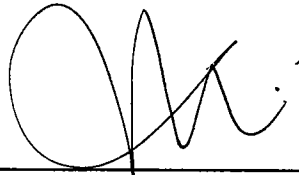
The above amendment is based on the stored and assigned relationships between the number of substrates and the processing time in the disclosed embodiment of the invention, as described in the specification at page 19, line 1- page 20, line 1, and illustrated in Fig. 5.

As now claimed, the storage device of claim 5 stores beforehand a relationship between the count of the substrates and the processing time such that the processing time for immersing the substrate in the heated treating solution is progressively extended as the substrates increase in number, and such that a fixed processing time is assigned to a predetermined range of counts of said substrates." None of the references (including particularly Park et al.) discloses or suggests a substrate treating apparatus having a storage device for storing such a relationship. Allowance of claims 5-16 is therefore requested.

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Respectfully submitted,

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